

CV – Tutor 2

Name: Dr. Chris J. Evans

Affiliation: Chief Metrologist/Senior Research Scientist, Zygo Corp R&D, USA

Relevant Experience: Major technical projects include: development of NIST's Precision Machining Research Facility comprising state of diamond turning, grinding and hard turning machines, polishing systems, and associated metrology; pathfinder metrology for the optics for the Laser Interferometric Gravitational Wave Observatory (LIGO); metrology systems for state of the art aspheric optics, photomask substrates, and very large plano optics.

Education: B.Sc., Chemical Engineering, University of Manchester Institute of Science and Technology, 1975

M.Sc., Precision Engineering, Cranfield Institute of Technology, 1987

Ph.D., Manufacturing Engineering, Birmingham University, 1996

Professional Experience: Butterworth Scientific, 1975-84; self-employed, 1984-85, U. S. Department of Commerce/NBS funded University of Wisconsin Research Associate based at NBS, 1985-89; U. S. Department of Commerce/NBS/NIST, Mechanical Engineer/Group Leader/Program Manager, 1989-2001; Zygo Corp R&D, 2001-date

Qualifications Summary: Expertise and experience in the following areas: nm-level metrology of optical surfaces and wavefronts; precision machine and machine system calibration and error correction; ultra-precision manufacturing and metrology process development; metrology over lateral scales from nm to metres. Authored or co-authored over 100 publications and a dozen patents or patent applications in precision engineering and metrology. Authored the book "Precision Engineering: and Evolutionary View" (1989) which has been translated and republished into Japan and, in a bilingual edition, in China in 2009

Professional Organizations: American Society for Precision Engineering; Charter Member, Director (1989-91, 1997-99), President (1998);

EUSPEN, member

Optical Society of America, Member

SPIE, Member

Fellow of CIRP – The International Academy for Production Engineering